

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Yoshiki KIDA, et al.

GAU:

SERIAL NO: New Application

EXAMINER:

FILED: Herewith

FOR: EXPOSURE APPARATUS, SURFACE POSITION ADJUSTMENT UNIT, MASK, AND DEVICE
MANUFACTURING METHOD

REQUEST FOR PRIORITY

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

☒ Full benefit of the filing date of U.S. Application Serial Number 09/899,171, filed July 6, 2001, is claimed pursuant to the provisions of 35 U.S.C. §120.

☐ Full benefit of the filing date(s) of U.S. Provisional Application(s) is claimed pursuant to the provisions of 35 U.S.C. §119(e): Application No. Date Filed

☒ Applicants claim any right to priority from any earlier filed applications to which they may be entitled pursuant to the provisions of 35 U.S.C. §119, as noted below.

In the matter of the above-identified application for patent, notice is hereby given that the applicants claim as priority:

<u>COUNTRY</u>	<u>APPLICATION NUMBER</u>	<u>MONTH/DAY/YEAR</u>
Japan	2000-207055	July 7, 2000
Japan	2000-235319	August 3, 2000

Certified copies of the corresponding Convention Application(s)

- ☐ are submitted herewith
- ☐ will be submitted prior to payment of the Final Fee
- ☒ were filed in prior application Serial No. 09/899,171 filed July 6, 2001
- ☐ were submitted to the International Bureau in PCT Application Number
Receipt of the certified copies by the International Bureau in a timely manner under PCT Rule 17.1(a) has been acknowledged as evidenced by the attached PCT/IB/304.
- ☐ (A) Application Serial No.(s) were filed in prior application Serial No. filed ; and
- ☐ (B) Application Serial No.(s)
 - ☐ are submitted herewith
 - ☐ will be submitted prior to payment of the Final Fee

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,
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